



Form PTO-1449		Docket Number (Optional) TSMC-02-212	Application Number 10/714,998
Applicant Bang-Chian Ho et al.		Filing Date 11/17/03	
Group Art Unit			

U. S. PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
CA	5573634	11/12/96	Ham	156	659.11	12/22/94
	6664011	12/16/03	Lin et al.	430	5	12/5/01
	5017461	5/24/91	Abe	430	325	3/13/89
	5998092	12/7/99	McCulloch et al.	430	270.1	5/27/98
	5948592	9/7/99	Umehara et al.	430	270.1	7/7/98
✓	5532113	7/12/96	Frechet et al.	430	296	9/21/95
✓	5536616	7/16/96	Frechet et al.	430	191	9/21/94
	5648196	7/15/97	Frechet et al.	430	270.1	7/14/95
	5858620	1/12/99	Ishibashi et al.	430	313	1/24/97
UA ✓	6319853	11/20/01	Ishibashi et al.	438	780	3/29/00

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Portmanteau Pages, Etc.)

PA	-	Co-pending U.S. Patent TSMC-01-376, Serial # 10/002,986, filed on 11/30/01, same assignee, "Improvement of Contact Hole Printing by Packing and Unpacking."
UA	-	Co-pending U.S. Patent TSMC-02-162, Serial # 10/443,359, filed on 05/22/03, same assignee, "Water Soluble Negative Tone Photoresist."

EXAMINER P. Ashton	DATE CONSIDERED 7/15/05
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

FEB 17 2004

(Use several sheets if necessary)

Application Number

10 | 714,998

Applicant

Bang-Chien Ho et al.

Final Date

11/17/03

Group Art Unit

OIP INFORMATION
 FEB 17 2004
 PATENT & TRADEMARK OFFICE
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[illegible]

FOREIGN PATENT DOCUMENTS

[illegible]

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

644	- Co-pending U.S. Patent TSMC-02-211, Serial # 10/268,586, filed on 10/10/02, same assignee, "Method for Preventing the Etch Transfer of Sidelobes in Contact Hole Patterns."

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R. Ashton

DATE CONSIDERED

7/15/05

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